

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	
Shigeyuki UZAWA et al.)	Examiner: R. A. Jarrett
)	Group Art Unit: 2125
Application No.: 09/864,309)	
)	Confirmation No.: 2803
Filed: May 25, 2001)	
)	
For: EXPOSURE APPARATUS, COATING/DEVELOPING)	
SYSTEM, DEVICE MANUFACTURING SYSTEM,)	October 10, 2006
DEVICE MANUFACTURING METHOD,)	(Tuesday after Federal
SEMICONDUCTOR MANUFACTURING FACTORY,)	Holiday)
AND EXPOSURE APPARATUS MAINTENANCE)	
METHOD)	

Mail Stop RCE

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

PRELIMINARY AMENDMENT

Sir:

Prior to further examination on the merits, please amend the above-identified application as follows: